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# **Cylindrical Langmuir probe measurements** in magnetized Helium plasma

J. Ledig, E. Faudot, N. Lemoine, S. Heuraux, J. Moritz.



## **Introduction & experimental setup**

■ Langmuir probe measurement is the most used technic to get access to plasma parameters :

- Plasma temperature  $T_e$
- Plasma density  $n_e$
- Plasma potential  $\phi_p$
- With external magnetic field : I(V) characteristics difficult to interpret (anisotropy effects ⇔ asymmetric effects between ion and electron current).

• Presented study on the role of RF-power, ||B||, and  $\vartheta$  (angle between probe and **B** direction)







Range of parameters explored in the scope of this study		
<b>RF power</b>	Magnetic field magnitude	<b>Angle</b> $\vartheta$ (probe, <b>B</b> )
From 20 to 200 W-RF	From 0 mT to 100 mT	From 0° to 90°
<b>Gaz</b> : Helium – <b>Pressure</b> : 1.2 Pa – <b>frequency</b> : 25 MHz – <b>Probe</b> : $r_p = 75 \mu m$ , $L_p = 1 cm$		



ALINE reactor : A LINEar plasma device L = 1 m, R = 35 cm. The axial magnetic field is created through 6 coils crossed by DC current from 0 to 220 A. The cylindrical probe is RF-compensated to ensure reliable measurements. The antenna (or RF – cathode) generates a RF field of 25 MHz.

-20 0 20 40 50

1. RF power supply

- 2. Arm of the Langmuir probe
- 3. Coils surrounding the vessel
- 4. Antenna and probe inside (3)

E. Faudot, RSI **86**, 063502 (2015)

Note : RF – capacitive discharges

were made in the frame of this work

A bump appears on the characteristics between the electron saturation current and the exponential part of I(V) in some conditions :

- $\rightarrow$  magnetic field must be strong enough
- $\rightarrow$  probe must not be to tilted

**B** confines the electrons ( $\rho_{ce} < \rho_{ci}$ )  $\Rightarrow$  the tube flux linked to the probe becomes narrow as **B** increases  $\Rightarrow$ asymmetric double probe behavior = only the plasma from the tube is probed.

Collecting surface if  $B \neq 0$  is not the whole probe but only a projection of it  $\Rightarrow$  linked flux tube wider if  $\vartheta > 0$ .





with collecting surface given by  $r_p$  plus some electron gyroradii,

 $S = \pi (\pi + N_0)^2 \times (2 \sqrt{\chi} + e^{\chi})$ 

$$S_{OML} = \pi (r_p + N\rho_{ce}) \times \left(2\sqrt{\frac{\alpha}{\pi}} + e^{\chi} \cdot \operatorname{erfc}\sqrt{\chi}\right)$$

Ion flux continuity:

$$\operatorname{div}(\Gamma_{i}) = S_{0} \Longrightarrow \oint_{\operatorname{tube}} \Gamma_{i} \cdot \mathrm{d}\boldsymbol{S} = \underbrace{\Gamma_{\parallel i} \cdot S_{\perp}}_{=0} + \Gamma_{\perp i} \cdot S_{\parallel} = \pi \rho_{ci}^{2} \times \frac{1}{2} e n_{0} \langle v_{\mathrm{TH}e} \rangle$$
  
Taking  $\rho_{ci} = v_{\perp i} / \omega_{c} \approx |\boldsymbol{E} \times \boldsymbol{B}| / \omega_{c} B^{2} = -\partial_{r} \phi / \omega_{c} B^{2}$  gives density:



## Conclusions

→ Use of cylindrical Langmuir probe imposes to be careful in magnetized plasmas : deformation of "classical" characteristics and apparition of a bump.

Probe Voltage [V]

40

50

20

- $\rightarrow$  Bump occurs if  $B \geq B_{\lim}$  and,

Probe Voltage [V]

- $B_{\lim} \text{ increases if incidence angle } \vartheta \text{ increases.} \\ B_{\lim} \text{ decreases if } RF Power \text{ increases } \Leftrightarrow n_e \text{ increases in plasma.} \end{cases} \Rightarrow B_{\lim} = f\left(\frac{\vartheta}{n_e}\right)$
- $\rightarrow$  Our stationary model displays an electron pumping mechanism.  $\rightarrow$  Bumps lead to bad evaluation of  $n_e$ ,  $T_e$  and  $\phi_p$ .  $\rightarrow$  Model suggests that  $\phi_p$  is on the top of the bump.  $\rightarrow$  Current and collecting surface dependence in sin  $\vartheta$ .
- $\Rightarrow$  Further studies are needed to get access to plasma parameters
- Model taking into account "real" RF-currents for  $\Gamma_{\perp}$
- Numerical model to find plasma parameters





Probe Voltage [V]